

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

INFORMATION DISCLOSURE STATEMENT		Docket Number 10191/1629	
Application Number To Be Assigned	Filing Date Herewith	Examiner To Be Assigned	Art Unit To Be Assigned
Title METHOD OF PLASMA ETCHING OF SILICON		Applicant(s) Franz LAERMER et al.	

Address to:
Assistant Commissioner
for Patents
Washington, D.C. 20231

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicant(s) hereby bring the following reference(s) to the attention of the Examiner. The reference(s) are listed on the attached modified PTO Form No. 1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
2. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated on the modified PTO form 1449.

Dated: 12/20/00

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